

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of:)	CONFIRMATION NO.: 7185
)	
Yasuo KOBAYASHI, et al.)	
)	
U.S. Serial No.: 10/549,859)	Group Art Unit: 1792
)	
Filed: June 6, 2006)	Examiner: Michael G. Miller
For: PLASMA-ASSISTED DEPOSITION METHOD AND PLASMA-ASSISTED DEPOSITION SYSTEM		

RESPONSE TO RESTRICTION REQUIREMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir :

A response to the Office Action mailed October 6, 2009 is due by November 6, 2009.
The Action required restriction between two patentably distinct inventions.

Applicants hereby elect Group I of claims 1-5, drawn to a plasma-assisted deposition method, for examination in this application.

Applicants reserve the right to file divisional application(s) for the non-elected claims in due course.

It is submitted that this application now is in condition for examination on the merits and early action in that regard is solicited.

Respectfully submitted,
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